## United States Patent [19]

## Sato

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[45] Date of Patent: \*\* Oct. 16, 1990

[54]	INSTRUMENT FOR DIAGONAL
	OBSERVATION BY MICROSCOPE

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[\*\*] Term: 14 Years
[21] Appl. No.: 187,416

[22] Filed: Apr. 28, 1988

[30] Foreign Application Priority Data

[56] References Cited

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[57] CLAIM

The ornamental design of an instrument for diagonal observation by microscope, as shown and described.

## **DESCRIPTION**

FIG. 1 is a front elevational view of an instrument for diagonal observation by microscope showing my new design;

FIG. 2 is a rear elevational view thereof;

FIG. 3 is a top plan view thereof;

FIG. 4 is a bottom plan view thereof;

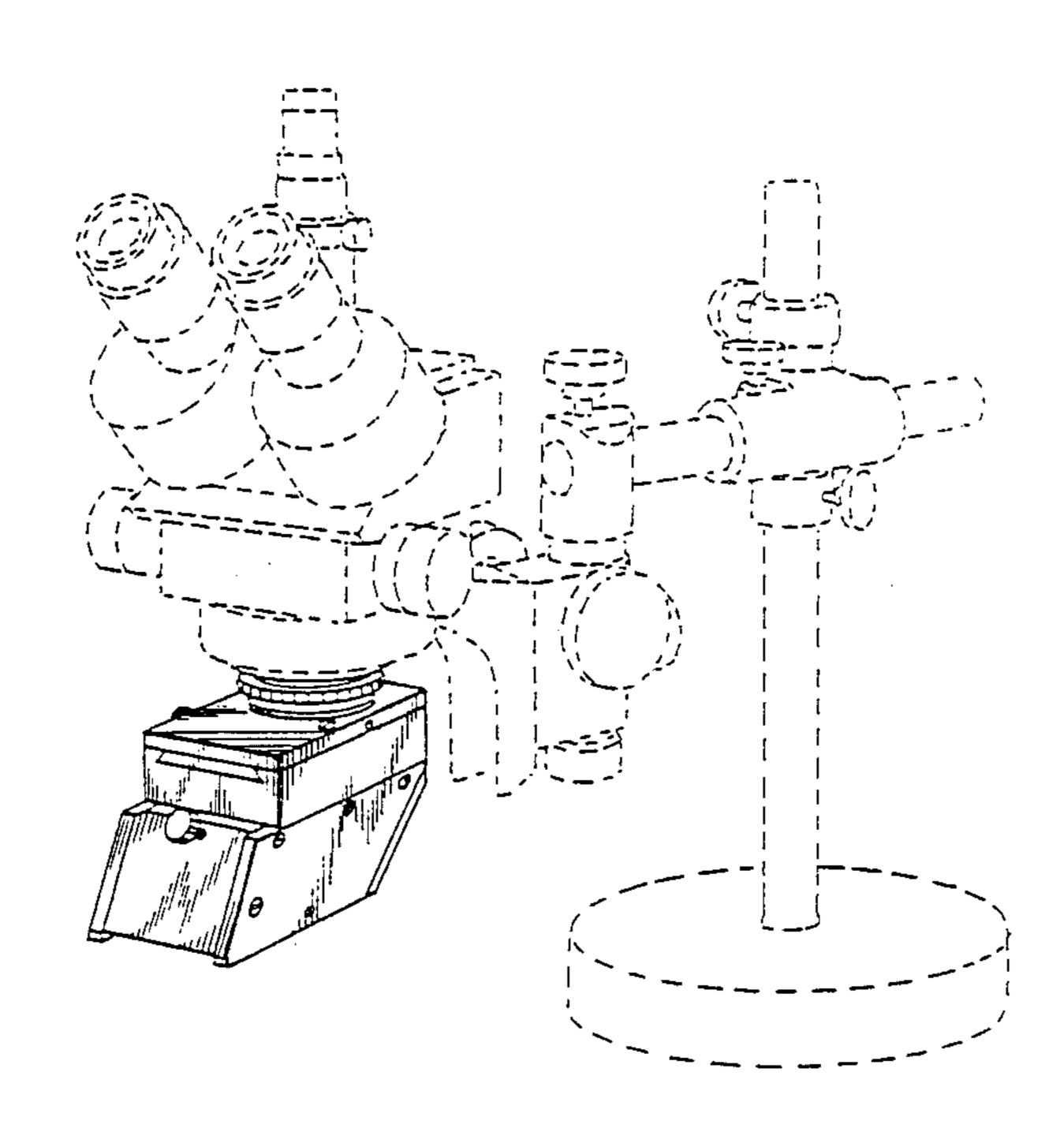
FIG. 5 is a left side elevational view thereof;

FIG. 6 is a right side elevational view thereof;

FIG. 7 is a sectional view taken along line VII—VII in FIG. 1;

FIG. 8 is a perspective view which illustrates the instrument mounted in association with a microscope, the latter being shown by broken lines for illustrative purposes only and forming no part of the claimed design; and

FIG. 9 is a right side elevational view similar to FIG. 6 illustrating a different operational state.



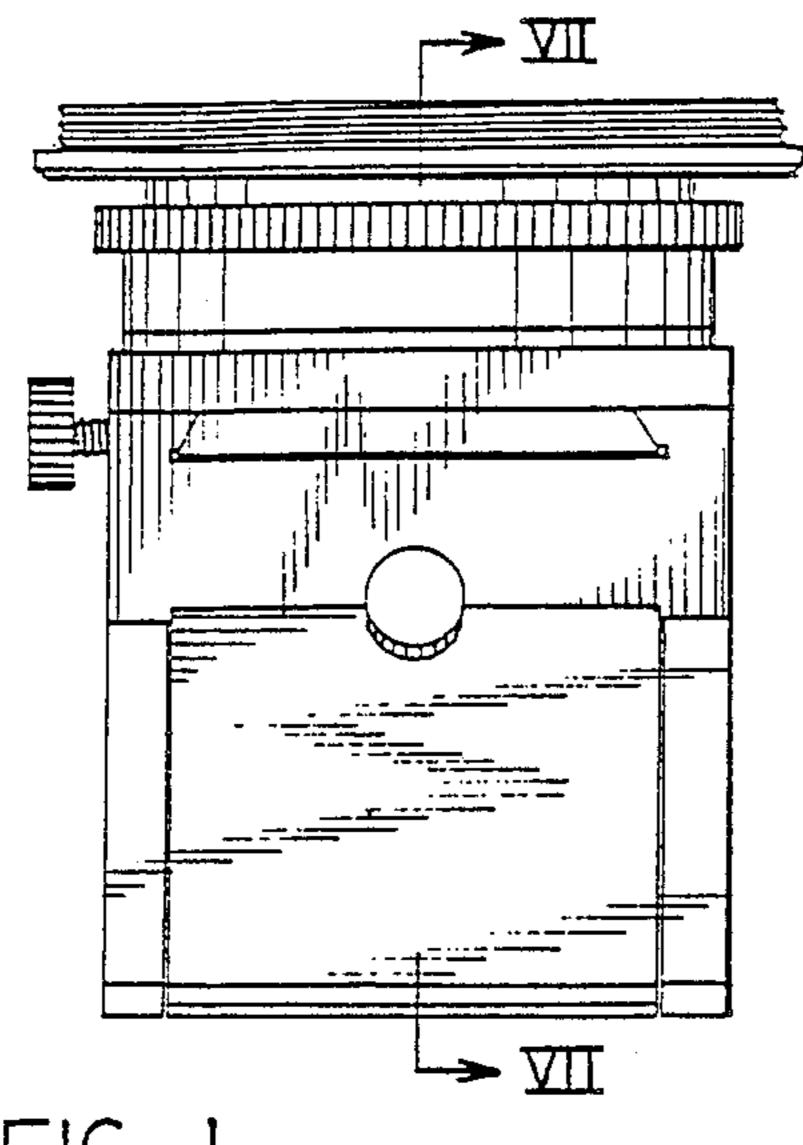


FIG. 1

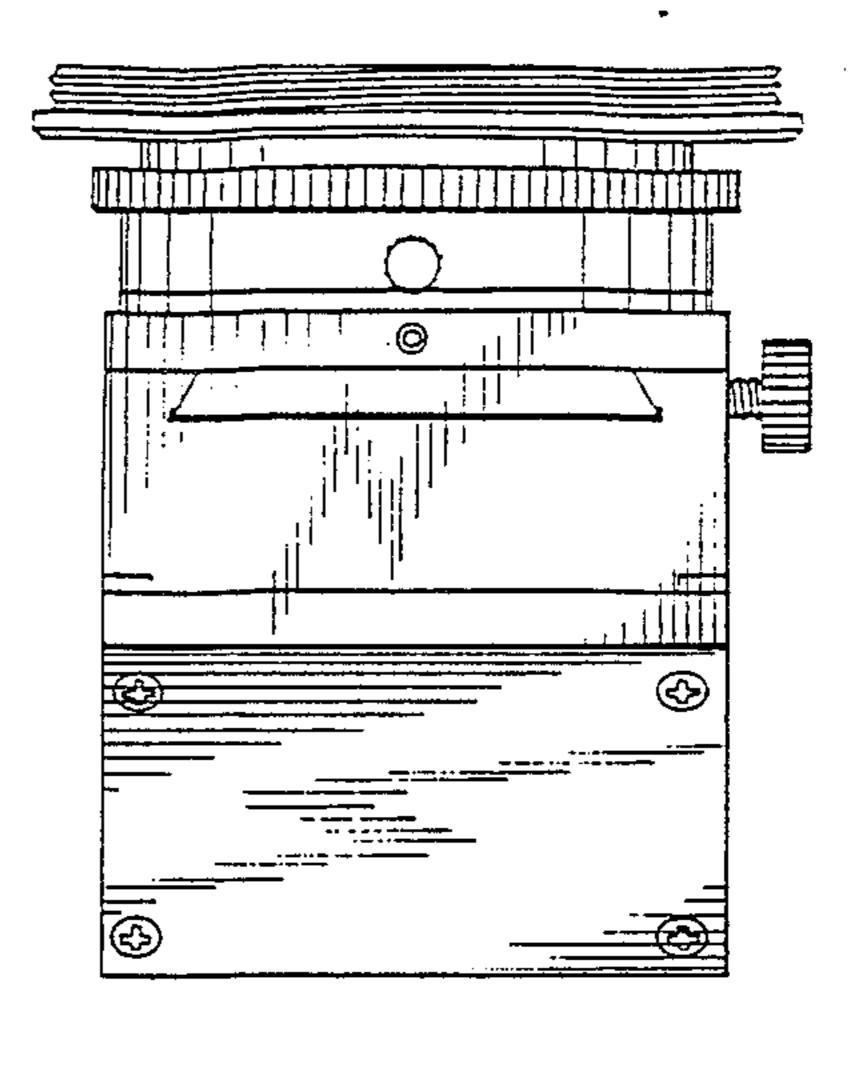


FIG. 2

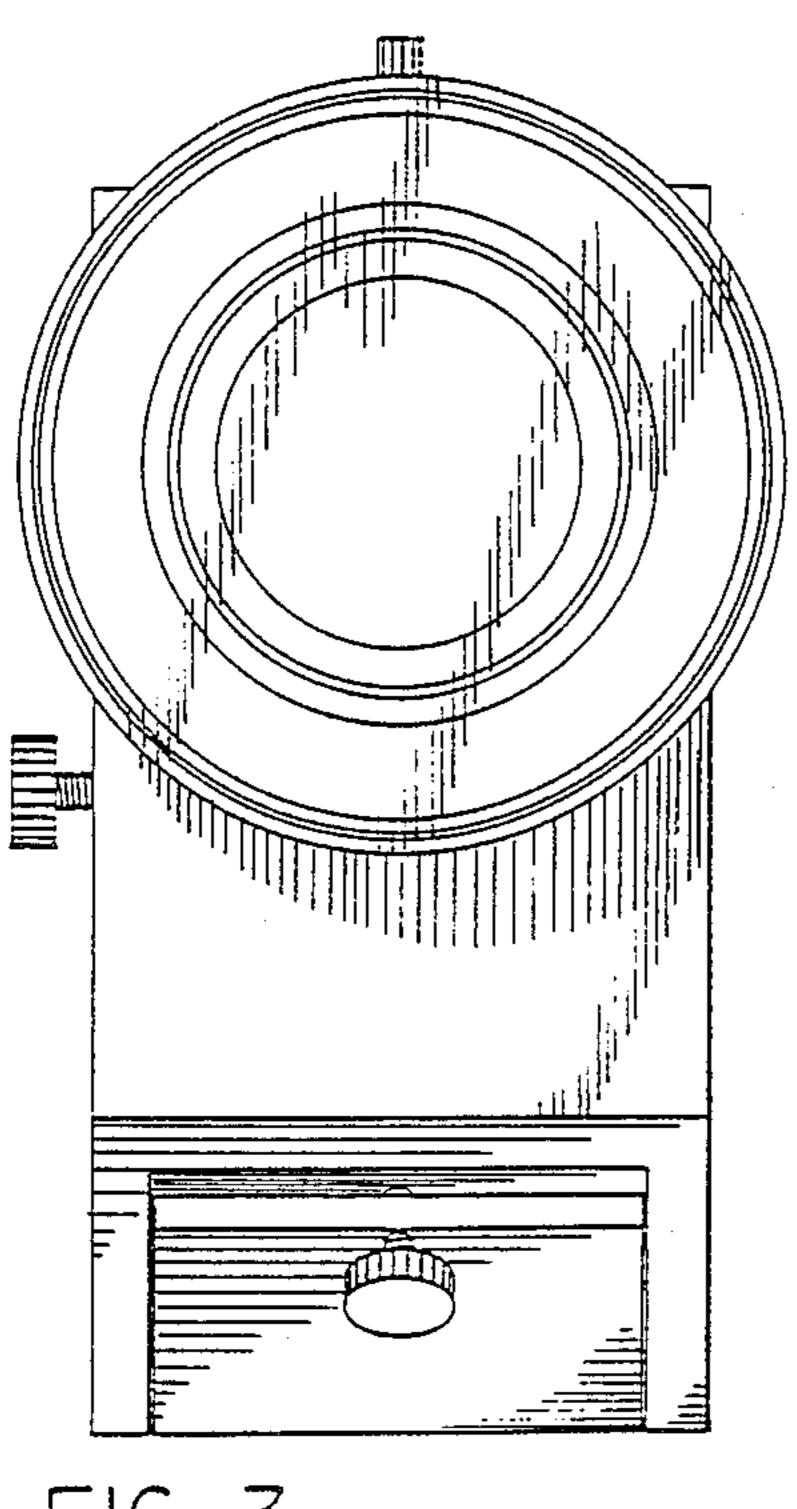


FIG. 3

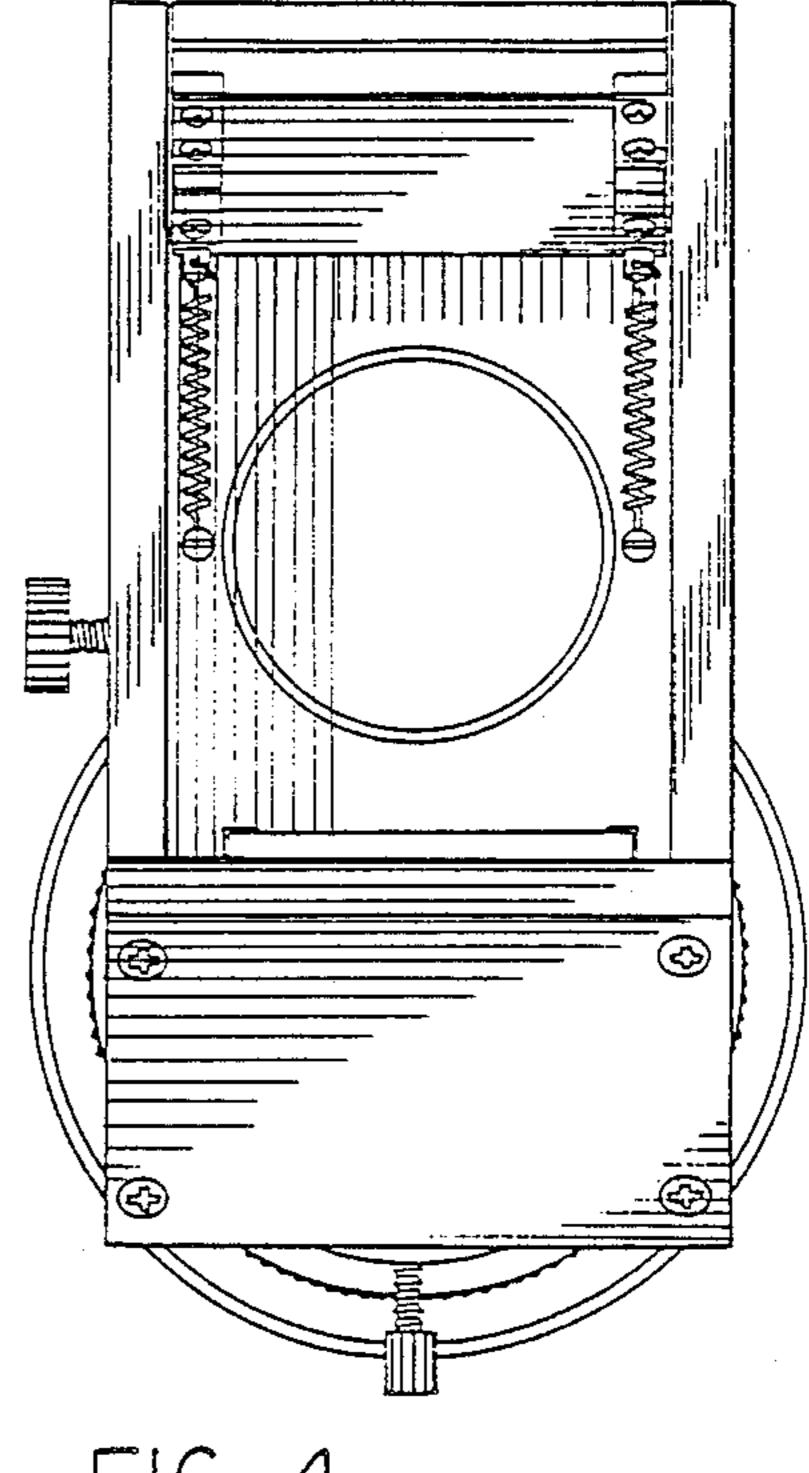
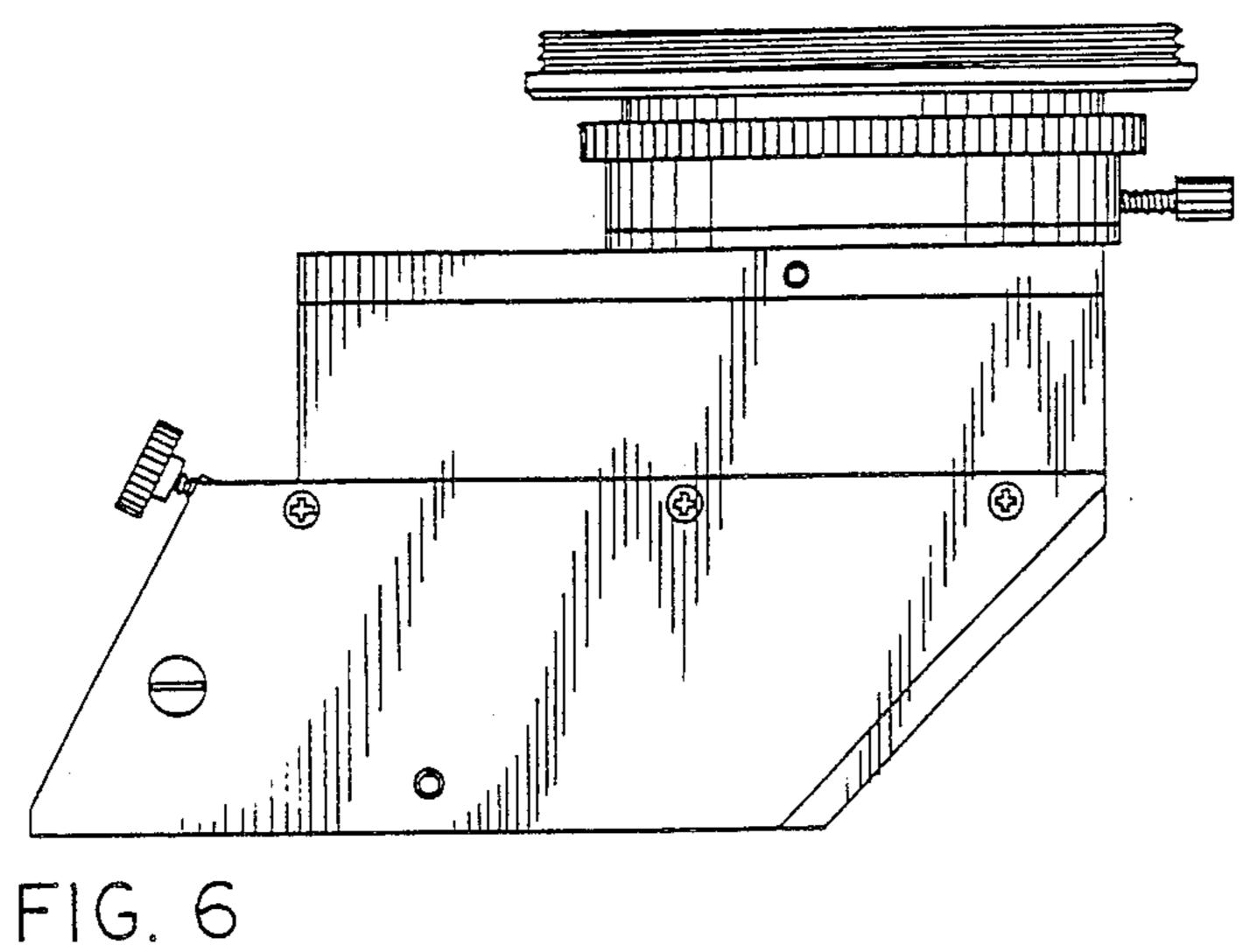


FIG. 4



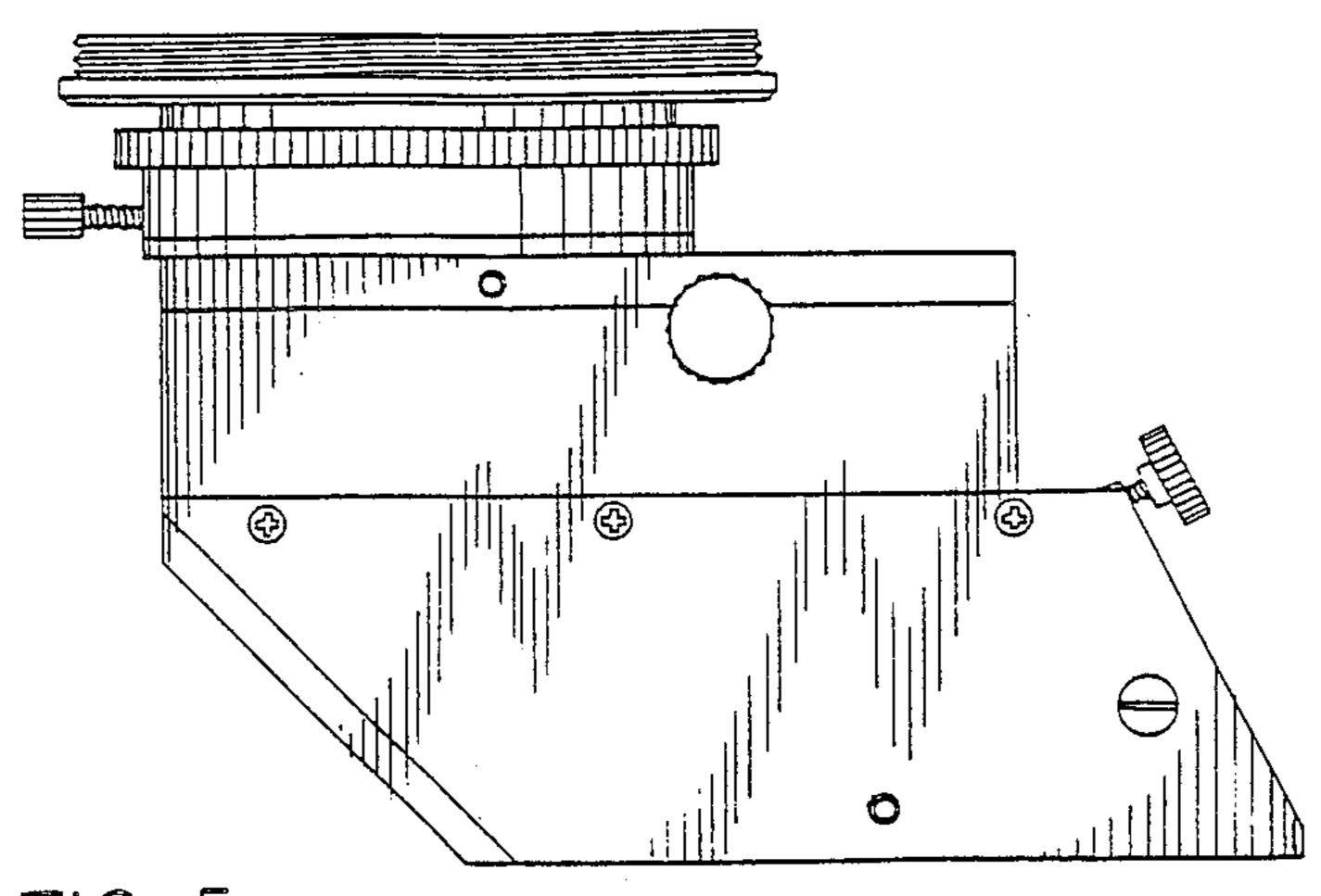


FIG. 5

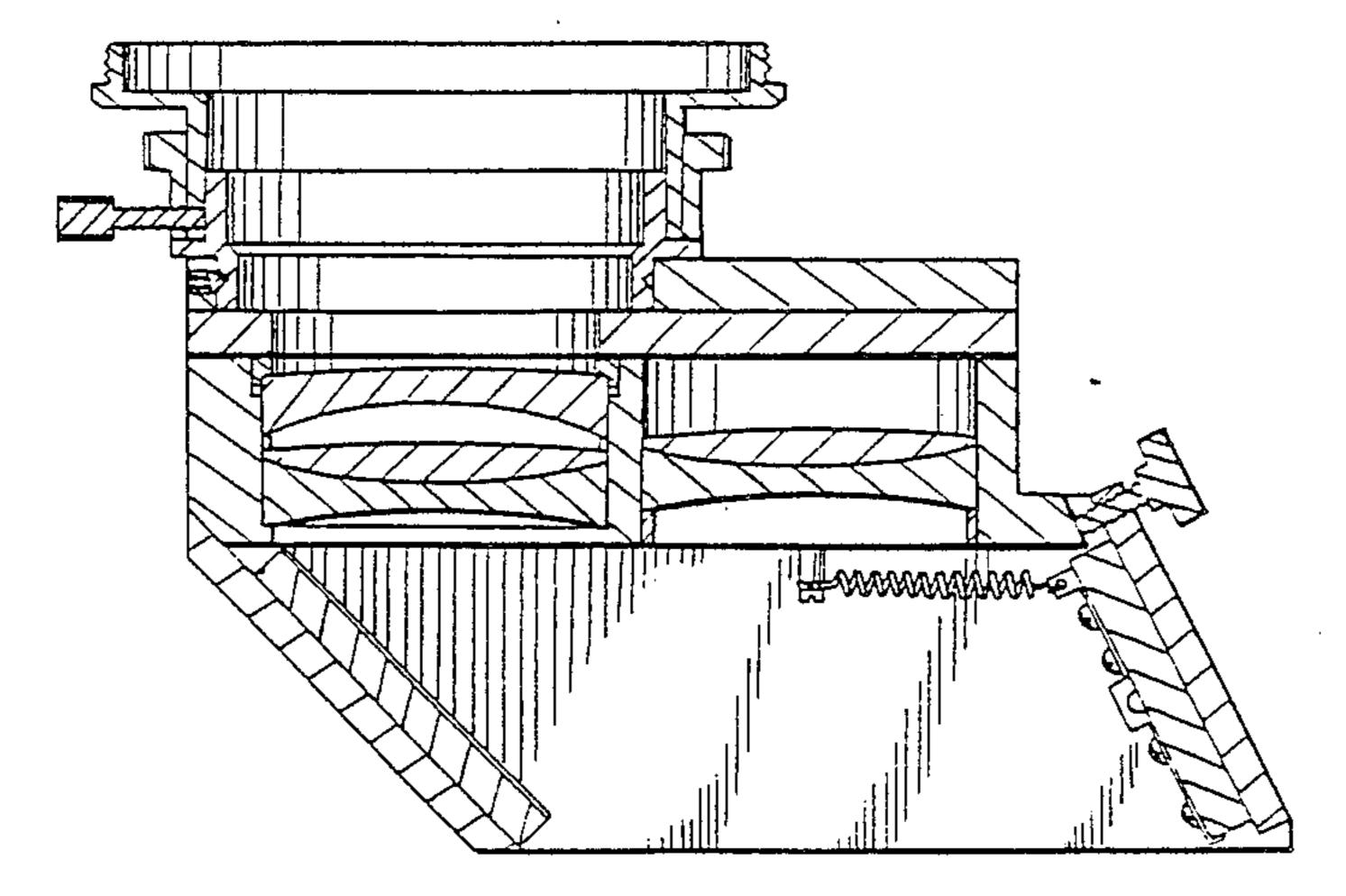
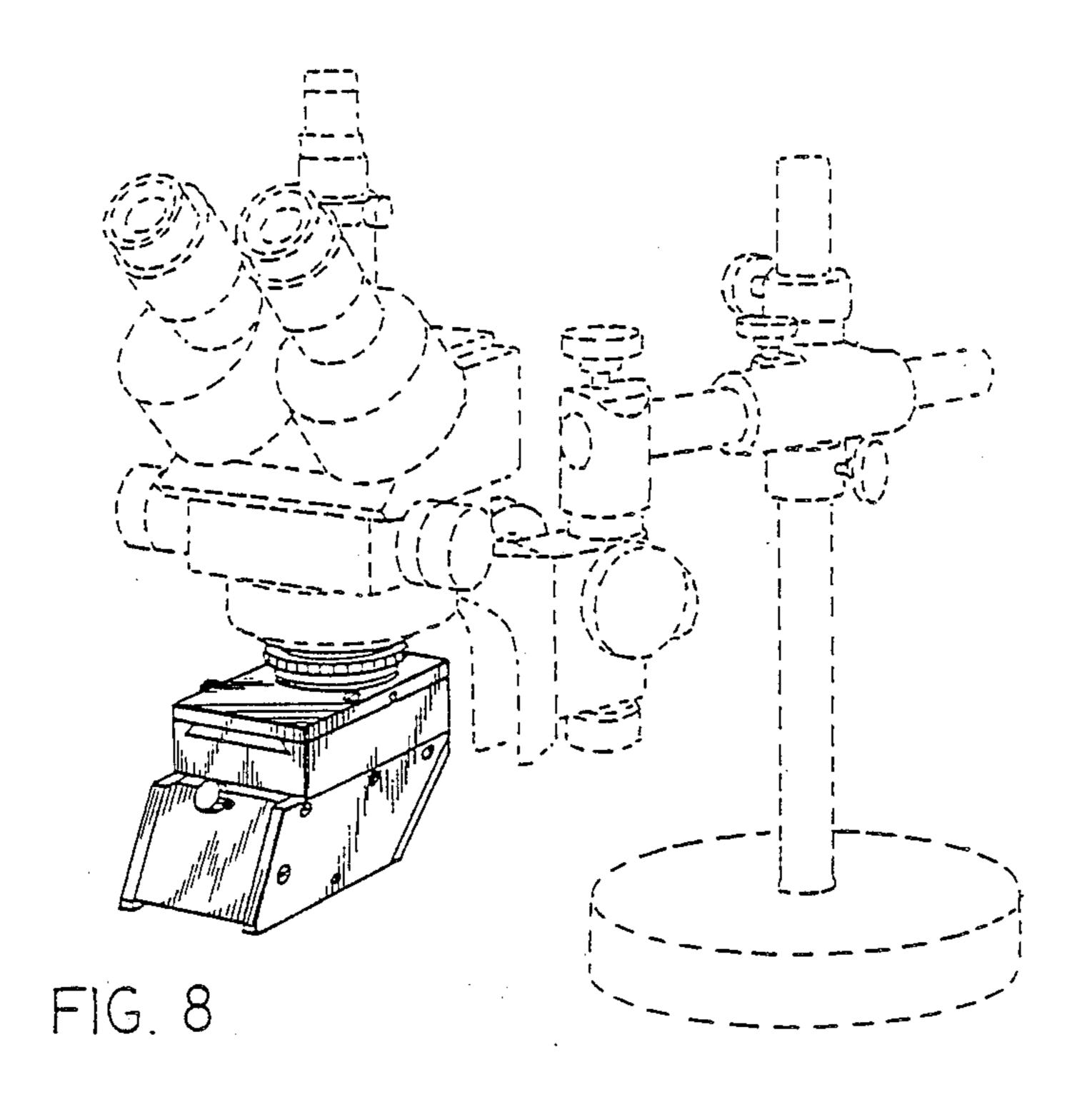


FIG. 7



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